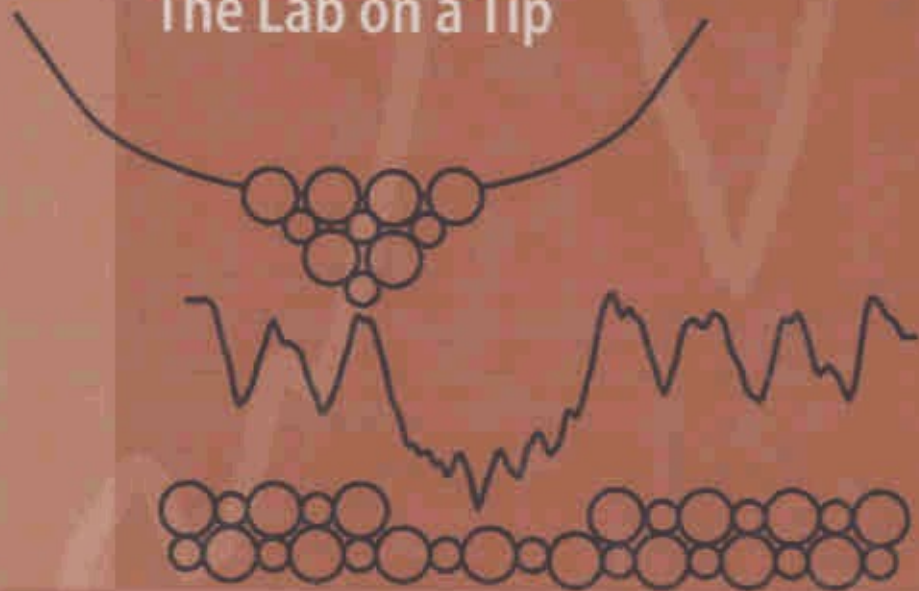


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Scanning Probe Microscopy

The Lab on a Tip



Springer

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